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PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Koichi KANAYA et al.

Group Art Unit: 1762

Application No.: 10/565,653

Examiner: K. CHEN

Filed: January 24, 2006

Docket No.: 126247

For: VAPOR DEPOSITION APPARATUS AND VAPOR DEPOSITION METHOD

AMENDMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In reply to the March 25, 2008 Office Action, the period for reply being extended by the Petition for Extension of Time filed herewith, please consider the following:

Amendments to the Claims as reflected in the listing of claims; and

Remarks.